

Transaction Information

Tool ID	LATK764 (F1 TRK370)
Tool Status	Running Wafers
Location	Singapore
Wafer Size	300 mm
Fab Section	Lithography
Tool Available Date	2021-09-01

General Product Information

Vendor Supplier	TEL
Model	LITHIUS i+
Vintage	2012
Serial No	G371244
Asset Description	TEL LITHUS i+ ARF IMMERSION TRACK
Software Version	3.00.71
CIM	SECS
Process	ARF IMMERSION

Hardware Configuration (Fab)

System Type	Description	Quantity	Status
Main System	ITC	3	OK
Main System	DEV	5	OK
Main System	COT	2	OK
Main System	BCT	3	OK
Main System	TCU	1	OK
Main System	PIR	2	OK
Main System	MAIN TOOL	1	OK
Handler System	CRA	1	OK
Handler System	PRA	3	OK
Handler System	IRAM	1	OK
Handler System	IRAI	1	OK
Factory Interface	FOUP	5	OK
Options System	NONE		
Others	NONE		

Hardware Configuration (Subfab / Auxilliary Units)

Description	Quantity	Status
AC Power Box	1	OK
COT CHEMICAL CABINET	1	OK
DEV CHEMICAL CABINETBOX	1	OK
Cup T&H CONTROLLER	2	OK

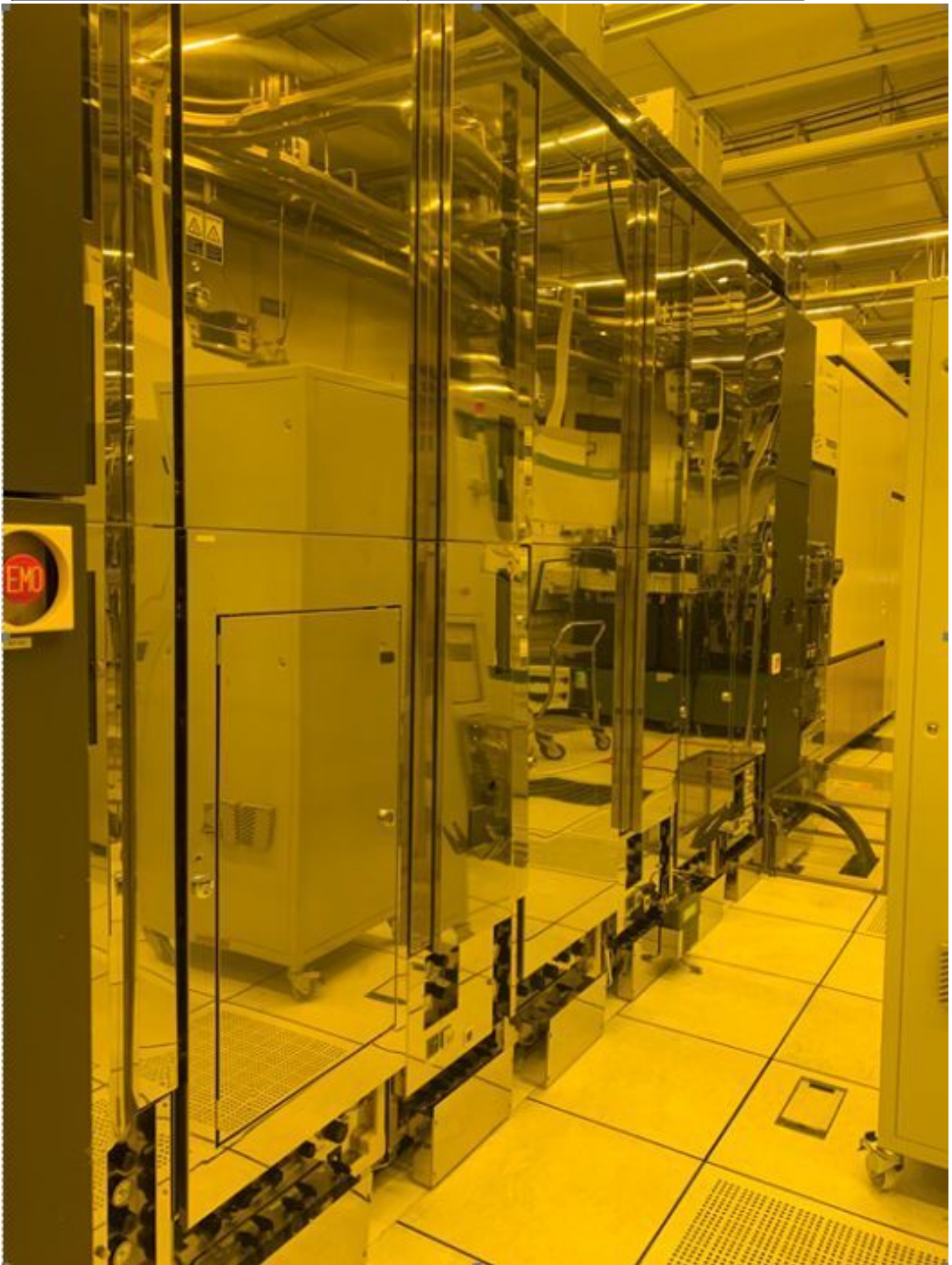
Missing/Faulty Parts / Accesories List

Description	Quantity
NONE	



Hardware Fab

Tool Hardware (Fab)



Hardware Fab

Tool Hardware (Fab)



Hardware Fab

Tool Hardware (Fab)



Hardware Sub-fab

Hardware (Sub-Fab) no missing parts



Manufacture Serial

Machine Serial Number

CLEAN TRACK



TOKYO ELECTRON KYUSHU LIMITED

MACHINE NO.

G371244

DATE

12/07

ADDRESS: 1-1 FUKUHARA KOSHI-SHI
KUMAMOTO 861-1116. JAPAN

Made in Japan

Hardware (Sub-Fab) no missing parts



Hardware (Sub-Fab) no missing parts



Hardware (Sub-Fab) no missing parts



Additional Configuration Files

Additional Configuration Files		
	Machine ID	G371244
	Software	3.00.71
	Tool Model	TEL LITHIUS i+
	Block	3 Blocks
CSB	Loadport	5
PRB1	BCT	3
	ADH	4
	HCP	6
	CLHR	6
	CPHP	5
PRB2	COT	2
	ITC	3
	HCP	3
	CLHR	5
PRB3	DEV	5
	EPHP	6
	HCP	2
	LHP	3
IFB	BWEE	1
	IHCP	2
	PIR	2
Others	Pump Type	Entegris RGEN-02 10cc
	Dev Nozzle Type	MGP Nozzle
Accessories	AC Power Box	1
	T&H Controller	Shinwa ME1 & ME2
	Chemical Cabinet	2